

ABSTRACTS

The present invention provides a substrate support member of an FPD manufacturing apparatus comprising: a substrate support plate on which a glass substrate is horizontally put , the substrate support plate having a plurality of vertical through-holes, each of the vertical though-holes having an upper distal portion of a shape of a reverse cone; and a plurality of lift pins being inserted into the respective vertical though-holes, the lift pins 32 being moved up and down so that the substrate 40 is raised from the substrate support plate 36 or put down on the substrate support plate 36, each of the lift pins having an upper distal portion of a shape of a reverse cone to comply with the upper distal portion of the corresponding vertical through-hole.

According to the present invention, since the lift pins has a shape of a reverse cone, not a stick, to be closely contacted to the substrate support plate 36, the temperatures and the potentials are equal between the substrate support plate 36 and the each of the lift pins 32. Therefore, it is advantageous that any specks are not generated on the substrate 40, and film-formation and etching can be uniformly made.